

3

FIG. 2 illustrates a circuit layout of a monolithic PIC according to one embodiment of the present invention. The PIC of FIG. 2 is fabricated on a semiconductor die 20 and includes a first output HVFET 23 having a set of relatively short interdigitated source/drain segments, and a second output HVFET 24 having a set of relatively long interdigitated source/drain segments. The segments of HVFETs 23 & 24 are placed on die 20 in a manner that optimizes the layout of control circuit 21. The arrangement of HVFETs 23 & 24 also improves the layout of the complete PIC such that die 20 has a lower aspect ratio as compared to prior art devices, even for implementations with low current handling capability.

As can be seen, output HVFET 23, with the short segments, is located on die 20 adjacent the short, lateral side of control circuit 21 and HVFET 23 both have substantially the same width (W_1). In this embodiment, HVFET 23 has a length (L_1) that is less than the length (L_2) of control circuit 21. The total length (L) of semiconductor die 20 is approximately equal to the sum of the lengths of HVFET 23 and control circuit 21 ($L \approx L_1 + L_2$).

In the embodiment of FIG. 2, output HVFET 24 is shown located on die 20 adjacent the long, bottom side of control circuit 21, and also extending beneath the length of HVFET 23. The length of the segments of output HVFET 24 is substantially equal to the length (L_2) of control circuit 21 plus the length (L_1) of the segments of output HVFET 23. In other words, the short HVFET segments are placed alongside the short side of control circuit 21 such that the combined control circuit and short HVFET segment length is substantially the same as the length of the long HVFET segments of transistor 24.

The total width (W) of semiconductor die 20 is approximately equal to the sum of the widths of control circuit 21 and HVFET 24 ($W \approx W_1 + W_2$). To manufacture a PIC device with increased current handling capability, more long segments are added in parallel to HVFET 24, which has the effect of increasing the W_2 dimension and lowering the aspect ratio of semiconductor die 20.

Practitioners in the integrated circuit and semiconductor fabrication arts will appreciate that the embodiment shown in FIG. 2 permits control circuit 21 to have a layout with a smaller aspect ratio than prior art designs. In the implementation shown in FIG. 2, the length (L_2) of control circuit 21 is about three times its width (W_1). Furthermore, the novel use and placement of multiple HVFETs having different segment lengths results in an aspect ratio closer to 1.0 for the complete PIC. This means that a family of PIC devices, each with different current handling capability, may be manufactured on a semiconductor die 20, each having an aspect ratio closer to 1.0. For the embodiment shown in FIG. 2, the aspect ratio of die 20 is about 1.6.

With continuing reference to FIG. 2, a PIC device having a relatively small current handling capability may be realized by connecting control circuit 21 to HVFET 23, but not to HVFET 24. A PIC device having increased current handling capability may be implemented by connecting control circuit 21 to both HVFET 23 and HVFET 24, or just to HVFET 24 and not HVFET 23. PIC devices that provide even larger current handling capability may be realized by increasing the number of long segment of HVFET 24 during the layout and manufacturing of semiconductor die 20. In each case, the dimensions of control circuit 21 remain the same. In accordance with the present invention, a complete family of PIC devices having a wide range of current handling capabilities may be implemented on a semiconductor die having an aspect ratio within a range of 0.5 to 2.0.

4

It should be understood that even though the embodiment of FIG. 2 illustrates two HVFETs with different length segments, there is no restriction on the number of HVFETs that may be included on die 20. That is, more than two HVFETs having different length segments may be included on die 20.

For example, a PIC with four output HVFETs may be implemented in which two additional HVFETs are located side-by-side on die 20 above or below HVFET 24. The two additional output HVFETs may have a combined segment length that is approximately equal to the sum of the lengths of HVFET 23 and control circuit 21 ($L \approx L_1 + L_2$). In such as case, the segment lengths of the two additional HVFETs may have an intermediate length that is longer than that of the short segments of HVFET 23, yet shorter than the length of the long segments of HVFET 24. These additional HVFETs with intermediate length segments may be selectively coupled to control circuit 21 to implement a PIC device providing an intermediate range of output current capacity.

FIG. 3 is a circuit schematic diagram that corresponds to the monolithic power integrated circuit shown in FIG. 2. As explained previously, control circuit 21 may be selectively coupled to output HVFET 23 or to output HVFET 24, or to both HVFETs 23 & 24. This latter case is depicted by the dashed line showing a common connection to each of the three terminals (i.e., source, drain, and gate) of the respective HVFETs. Alternatively, the HVFETs may have only one or two terminals coupled together (i.e., only the source terminals).

Persons of ordinary skill in the integrated circuit and semiconductor arts will appreciate that selective coupling between control circuit 21 and one or both of the output HVFETs 23 & 24 may be achieved utilizing a variety of conventional techniques and circuits. For example, an optional metal connection may be implemented during the layout and fabrication of the PIC. Alternatively, an ordinary on-chip switching circuit may be utilized for selectively coupling one or more of the output HVFETs to control circuit 21. This switching circuit may be incorporated into the layout of control circuit 21 and may comprise one or more transistor switching devices (e.g., transmission gates).

Although the present invention has been described in conjunction with specific embodiments, those of ordinary skill in the arts will appreciate that numerous modifications and alterations are well within the scope of the present invention. Accordingly, the specification and drawings are to be regarded in an illustrative rather than a restrictive sense.

I claim:

1. A method of manufacturing a monolithic power integrated circuit (PIC) on a semiconductor die, the method comprising:

locating a control circuit in a first area of the semiconductor die, the control circuit having a length that extends along a first side and a width that extends along a second side;

locating a first output high voltage field-effect transistors (HVFET) adjacent the second side of the control circuit, the first output HVFET having a width substantially equal to the width of the control circuit;

locating a second output HVFET adjacent the first side of the control circuit, the second output HVFET having a length substantially equal to the length of the control circuit plus a length of the first output HVFET; and coupling the control circuit to at least one of the first or second output HVFETs.